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MICRON.071DV1APPLICATION NO.  
10/060,842

SHEET 1 OF 1

INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT

(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT  
RainaFILING DATE  
January 29, 2002GROUP  
2877

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
GP	1.	4,125,446	11/14/78	Hartsough et al.			
	2.	4,792,842	12/20/88	Honma et al.			
	3.	5,147,819	09/15/92	Yu et al.			
	4.	5,229,331	07/20/93	Doan et al.			
	5.	5,358,908	10/25/94	Reinberg et al.			
	6.	5,372,973	12/13/94	Doan et al.			
	7.	5,923,953	7/13/99	Goldenberg Barany et al.			
	8.	6,154,188	11/28/00	Learn et al.			

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

## OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

GP	9.	Takagi et al., "P2.2-3 Characterization of Al-Nd Alloy Thin Films for Interconnections of TFT-LCDs" Asia Display 1995, 4 pages.					
GP	10.	Takayama et al., "Al-Sm and Al-Dy alloy thin films with low resistivity and high thermal stability for microelectronic conductor lines", Thin Solid Films 289, 1996 pp. 289-294.					
GP	11.	Kim et al., "22.2 Pure Al and Al-Alloy Gate-Line Processes in TFT-LCDs", SID 96 Digest, pp. 337-340.					

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EXAMINER	<i>Yoon Jang</i>	DATE CONSIDERED	5/28/03
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